

<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>	<b>Docket Number (Optional)</b> <b>TWI-31500</b>	<b>Application Number</b> <b>09/938,415</b>
	<b>Applicant(s)</b> <b>Kenneth C. Johnson et al.</b>	
	<b>Filing Date</b> <b>August 23, 2001</b>	<b>Group Art Unit</b> <b>2851</b>

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
AS	AA	5,867,276	02/02/1999	McNeil et al.	356	445	03/07/1997
AS	AB	5,963,329	10/05/1999	Conrad et al.	356	372	10/31/1997


**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

**OTHER DOCUMENTS**

*(Including Author, Title, Date, Pertinent Pages, Etc.)*

AS	AC	J. Allgair et al., "Manufacturing Considerations for Implementation of Scatterometry for Process Monitoring," <i>In Metrology, Inspection, and Process Control for Microlithography XIV, Proceedings of SPIE</i> , Vol. 3998 (2000), pp. 135-134.					
AS	AD	J. Bao et al., "Specular Spectral Profilometry on Metal Layers," <i>In Metrology, Inspection, and Process Control for Microlithography XIV, Proceedings of SPIE</i> , Vol. 3998 (2000), pp. 882-892.					

<b>Examiner</b> 	<b>Date Considered</b> <b>9/23/04</b>
<b>Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</b>	